

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1-15. (cancelled)

1 16. (currently amended): A method for fabricating a GMR read head portion of a magnetic
2 head, comprising:

3 fabricating a bottom magnetic shield layer;

4 fabricating a ~~bottom~~ first electrically insulating layer upon said bottom magnetic shield
5 layer;

6 ~~fabricating a GMR read sensor including a plurality of films;~~

7 fabricating a first electrical conductor layer on a surface plane of said ~~GMR read sensor~~
8 first electrically insulating layer;

9 fabricating a monolayer photoresist mask upon said first electrical conductor layer, said
10 etching mask including a read width trench formed therethrough;

11 reactive-ion-etching said first electrical conductor layer through the read width trench to
12 create two ~~first~~ electrical conductor ~~layers~~ leads;

13 fabricating a GMR read sensor including a plurality of films;

14 fabricating a second electrically insulating layer above said GMR read sensor layer; and

15 fabricating a top magnetic shield layer upon said second electrically insulating layer.

1 17. (currently amended): A method for fabricating a GMR read head portion of a magnetic
2 head, as described in claim 16, wherein said two ~~first~~ electrical conductor ~~layers~~ leads are formed

3 with opposing end faces that result from the reactive-ion-etching, wherein said end faces are
4 generally perpendicular to a film surface of said GMR read sensor.

1 18. (withdrawn): A method for fabricating a read head portion of a magnetic head, as
2 described in claim 17, wherein the step of fabricating a GMR read sensor including a plurality
3 films is performed before the steps of fabricating a first conductor layer, and fabricating a
4 monolayer photoresist mask, and reactive-ion-etching a read width.

1 19. (cancelled):

1 20. (withdrawn): A method for fabricating a read head portion of a magnetic head as
2 described in claim 18, further including the step of fabricating a longitudinal bias (LB) layer
3 proximate said GMR read sensor.

21-25. (cancelled)

26. (new): A method for fabricating a read head portion of a magnetic head as described in
claim 16, further including the step of fabricating a longitudinal bias (LB) layer proximate said
GMR read sensor.